

## Abstract of the Disclosure

An inspection apparatus by which an increased number of semiconductor devices can be inspected simultaneously. The inspection apparatus includes a driver for outputting a signal to be used for inspection, a branching point to which the output terminal of the driver is connected, a current limiting element interposed between each of the terminals of the semiconductor devices to be inspected and the branching point, and a capacitor connected in parallel to each of the current limiting elements. A resistor or a thermistor, for example, is used for the current limiting element.